

FORM PTO-1449  
(REV. 7-90)

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO.  
**BA-22772**

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APPLICANT  
**YEAN-KUEN FANG, Et Al**

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10/085256  
10/22/01  
JCS28 U.S. PTO

**U.S. PATENT DOCUMENTS**

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>NY</i>	AA	6 0 4 0 9 0 0	3/21/00	Chen	356	35.5	
	AB	4 4 4 2 7 1 7	4/17/84	Kurtz et al	73	766	
	AC	6 0 4 4 7 0 5	4/04/00	Neukermans et al	73	504.02	
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

**FOREIGN PATENT DOCUMENTS**

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
	AL						
	AM						
	AN						
	AO						
	AP						

**OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)**

<i>NY</i>	AR	<input checked="" type="checkbox"/>	M. Zhang, et al, "Frictional Action at Lower Limb/Prosthetic Socket Interface", Med. Eng. Phy. Vol. 18, No. 3, pp 207-214, 1996
<i>NY</i>	AS	<input checked="" type="checkbox"/>	M. Zhang, Arthur F.T. Mak, "A Finite Element Analysis of the Load, etc.", IEEE Transactions on Rehab. Eng., Vol. 4, No. 4, pp 337-346, 1996
<i>NY</i>	AT	<input checked="" type="checkbox"/>	Jyh-Jier Ho, et al, "Development of a Micro-Electro-Mechanical System Pressure Sensor for Rehabilitation Engineering Applications", International J. of Electronics, Vol. 87. No. 6, pp 757-767. (2000)

EXAMINER

DATE CONSIDERED

*8/25/03*

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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	AN							
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	AP							

## OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

MU	AU	Chang Liu, et al, "A Micromachined Flow Shear-Stress Sensor Based on Thermal Transfer Principles", J. of MEMS, Vol.8, No. 1, pp90-99, 1999
NV	AV	Tao Pan, et al, "Microfabricated Shear Stress Sensors, Part 1: Design and Fabrication", AIAA J., Vol.37, No. 1, pp66-72, 1999
AW	AW	Javad Shajii, et al, "A Micromachined Floating-Element Shear Stress Sensor Using Wafer-Bonding Technology", J. of MEMS, Vol.1, No.2, pp89-

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8/27/94, 1992

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PTO-1449  
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FOREIGN PATENT DOCUMENTS									
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	AM								
	AN								
	AO								
	AP								

**OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)**

MW	AX	A. Padmanabhan, et. al. "Micromachined sensors for static and dynamic shear-stress measurement in aerodynamic flows," Transducers' 97, pp. 137-140. 1997
MV	AS	
	AT	

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DATE CONSIDERED 8.25.1

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